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PHINPhotoinjector as the CLIC Drive Beam e- Source

Dr. Öznur**METE**

CERN, European Laboratory for Nuclear Research

On behalf of the PHIN Team



Preface, the original contribution in a deductive view of the CLIC project

- Compact Linear Collider Project
- What have we achieved in the third phase of the CLIC test facility?
- Quest for an adequate electron source for the CLIC drive beam (thermionic or laserdriven)

PHIN photoinjector, objectives of the research

- What is a photoinjector?
- Intro to PHIN photoinjector
- Objectives of the research program

Beam instrumentation & characterization, commissioning highlights of PHIN

- Properties of the laser, cathode and the charge production studies
- RF gun for PHIN
- High intensity electron beam diagnostics at the injector stage (@high charge, low energy)
- Some of the highlights from the characterization of our system

More, more and more (backup)

Conclusions

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FACT The quality of the main beam acceleration depends on the quality of the drive beam.

MISSION The choice and optimization of the drive beam injector...

A former step towards the CLIC-DB



The continuous 1.6 µs long drive beam pulse is generated by a thermionic gun,

A former step towards the CLIC-DB



- The continuous 1.6 µs long drive beam pulse is generated by a thermionic gun,
- then, time structure is produced by
 - ▶ three 1.5 GHz sub-harmonic bunchers
 - ▶ a S-band pre-buncher
 - a traveling wave buncher

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The existing thermionic gun for the CLIC Test Facility 3



- The 1.6 µs long drive beam pulse is generated by a 140 kV, 9 A thermionic triode gun,
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Streak camera measurements can reveal the parasitic charge.



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- Compactness, flexibility, stability?



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- An **RF cavity** is used for rapid acceleration of the electrons after the emission.
- Solenoid magnets are placed in order to focus the space charge dominated beam and achieve the emittance compensation.

A photoinjector in a nutshell

A Photoinjector project for CTF3 and for future CLIC-DB source.



A photoinjector in a nutshell

A Photoinjector project for CTF3 and for future CLIC-DB source.



- A photoinjector with the specifications of CTF3 thermionic gun.
- The project is in the framework of the "Coordinated Accelerator Research in Europe (CARE)" program.
- A collaboration...

"Laboratoire de l'Accélérateur Linéaire (LAL)"

RF gun

"Rutherford Appleton Laboratory (RAL)"

Laser

"European Organization for Nuclear Research (CERN)"

Photocathode production,

Overall coordination

Commissioning

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- ▶ 1.2 µs long pulse train generation with 1908 bunches,
- challenging stability requirements: amplitude (charge) stability requirement of 0.25%,



A photoinjector in a nutshell



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- Eventually, to study the consequences of the findings to constitute a preliminary RF gun design for CLIC-DB injector.

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 Continuous pulses from Nd:YLF oscillator @ 1.5 GHz,





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- Illuminates a Cs2Te cathode







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Consistency with theoretical prediction.






















OTR Profiling



OTR Profiling



 Charged particles emit Optical Transition Radiation (OTR) while crossing a boundary with different dielectric properties.

Segmented

Dump

Dipole

Magnet

Spectrometer

166.5

.. 286.1

FC

MTV2 261.1

OTR Profiling



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- OTR is used to measure the beam profile as a diagnostics tool.

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Multi-Slit

Mask

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- OTR can be detected by a ICCD (Intensified Charge Coupled Device) camera,
- Gateability of ICCD is used for the time-resolved measurements.







Monitoring the OTR Image of the Beam

Beam size



Beam size

Single Shot Solenoid Scan



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Beam Size along the Pulse Train

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- Beam size can be measured as a time-resolved manner along the pulse train.

Beam size

Beam Size along the Pulse Train



Beam size

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Beam size

























PHIN Photoinjector as the CLIC-DB e- Source / ICPP / 24 June 2011

According to the MS method

- ▶ The MS mask is introduced in front of the beam,
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- Development of an analysis method and producing several algorithms by considering <u>different</u> <u>background (noise) patterns</u>.



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- PHINEMA: PHIN photo-injector Emittance Measurement and Analysis software

MTV1

141.5



Emittance

Beam Instrumentation & Characterization

Emittance

Data Analysis



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Beam Instrumentation & Characterization

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 - reconstruction of the phase space.

Emittance



Beam Instrumentation & Characterization

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Beam Instrumentation & Characterization

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Time-Resolved Emittance Measurement

Beam Instrumentation & Characterization



Time-Resolved Emittance Measurement



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 Variation becomes visible with the increasing resolution along the pulse train.



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- "Usual suspects": Laser intensity fluctuations or RF pulse shape?

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Time-Resolved Emittance Measurement

- Variation becomes visible with the increasing resolution along the pulse train.
- "Usual suspects": Laser intensity fluctuations or RF pulse shape?
- A correlation between RF pulse shape and the emittance variation along the pulse train has been determined.













A magnetic spectrometer has been used for the energy measurements.

Principle: measurement of the beam momentum distribution after a dipole with a known magnetic field.





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- Principle: measurement of the beam momentum distribution after a dipole with a known magnetic field.
- Beam momentum distribution can be measured by an OTR profile monitor or a segmented dump.



OTR Monitoring



Energy Measurements with a Magnetic Spectrometer

OTR Monitoring



OTR Monitoring



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Parameter

RF

RF Gradient (MV/m) RF Frequency (GHz) **Electron Beam** Charge per Bunch (nC) Charge per Train (nC) Train Length (ns) Number of Bunches/Train Current (A) Normalized Emittance (mm mrad) Energy (MeV) Energy Spread (%) Laser and Cathode Charge Stability (%) Cathode Quantum Efficiency (%) UV Laser Energy / Pulse (nJ) Micropulse Repetition Rate (GHz) Macropulse Repetition Rate (Hz)

Parameter	Specification	
RF		
RF Gradient (MV/m)	85	
RF Frequency (GHz)	2.99855	
Electron Beam		
Charge per Bunch (nC)	2.33	
Charge per Train (nC)	4446	
Train Length (ns)	1273	
Number of Bunches/Train	1908	
Current (A)	3.5	
Normalized Emittance (mm mrad)	<25	
Energy (MeV)	5.5	
Energy Spread (%)	≤1	
Laser and Cathode		
Charge Stability (%)	<0.25	
Cathode	Cs2Te	
Quantum Efficiency (%)	3	
UV Laser Energy / Pulse (nJ)	370	
Micropulse Repetition Rate (GHz)	1.5	
Macropulse Repetition Rate (Hz)	1-5	
Parameter	Specification	Achieved
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RF		
RF Gradient (MV/m)	85	85
RF Frequency (GHz)	2.99855	2.99855
Electron Beam		
Charge per Bunch (nC)	2.33	4.4
Charge per Train (nC)	4446	5800
Train Length (ns)	1273	1300
Number of Bunches/Train	1908	1950
Current (A)	3.5	6.6
Normalized Emittance (mm mrad)	<25	14
Energy (MeV)	5.5	5.5
Energy Spread (%)	≤1	0.7
Laser and Cathode		
Charge Stability (%)	<0.25	0.8-2.4
Cathode	Cs2Te	Cs2Te
Quantum Efficiency (%)	3	18 (peak)
UV Laser Energy / Pulse (nJ)	370	400
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- A feedback stabilization system is planned to be built for the laser intensity stability in order to improve the charge stability.

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- All the specifications have been fulfilled during the commissioning (except the charge stability)
- A feedback stabilization system is planned to be built for the laser intensity stability in order to improve the charge stability.
- Correlation between the electron beam, the laser and the RF pulse shape has been understood via the measurements along the pulse train.

Parameter	Specification	Achieved
RF		
RF Gradient (MV/m)	85	85
RF Frequency (GHz)	2.99855	2.99855
Electron Beam		
Charge per Bunch (nC)	2.33	4.4
Charge per Train (nC)	4446	5800
Train Length (ns)	1273	1300
Number of Bunches/Train	1908	1950
Current (A)	3.5	6.6
Normalized Emittance (mm mrad)	<25	14
Energy (MeV)	5.5	5.5
Energy Spread (%)	≤1	0.7
Laser and Cathode		
Charge Stability (%)	<0.25	0.8-2.4
Cathode	Cs2Te	Cs2Te
Quantum Efficiency (%)	3	18 (peak)
UV Laser Energy / Pulse (nJ)	370	400
Micropulse Repetition Rate (GHz)	1.5	1.5
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- All measurement results can be reproduced successfully by the single bunch PARMELA simulations.

Conclusions

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as a consequence:

- The conceptual study of a 1 GHz **RF gun with the CLIC-DB specifications** has been initiated,
- The preliminary beam dynamics simulations have been performed
- ▶ The results have been compared with the ongoing CLIC-CDR baseline thermionic injector studies for CLIC DB,
- ▶ The photoinjector option has been emphasized as a **DB source candidate**.

back-up contents

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- A general remark on the beam emittance regardless of the type of the injector.

Thank you very much for your attention.

BACK-UP SLIDES

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- Distance between the screen and the mask,
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Error on the mean position, σ_x (mm)	0.01
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$$\begin{split} \sigma_{\epsilon}^{2} &= \frac{(\rho_{j}x_{j}'^{2})^{2}(4\rho_{i}^{2}x_{i}^{2}\sigma_{x_{i}}^{2} + x_{i}^{4}\sigma_{\rho_{i}}^{2})}{4\epsilon^{2}(\sum_{i=1}^{N}\rho_{i})^{4}} \\ &+ \frac{(\rho_{j}x_{j}^{2})^{2}(4\rho_{i}^{2}x_{i}'^{2}\sigma_{x_{i}}^{2} + x_{i}'^{4}\sigma_{\rho_{i}}^{2})}{4\epsilon^{2}(\sum_{i=1}^{N}\rho_{i})^{4}} \\ &+ \frac{(\rho_{i}^{2}x_{i}'^{2}\sigma_{x_{i}}^{2} + \rho_{i}^{2}x_{i}^{2}\sigma_{x_{i}}^{2} + x_{i}^{2}x_{i}'^{2}\sigma_{\rho_{i}}^{2})(\rho_{i}x_{i}x_{i}')^{2}}{\epsilon^{2}(\sum_{i=1}^{N}\rho_{i})^{4}} \\ &- \frac{2(\sum_{i=1}^{N}\rho_{i}x_{i}^{2})(\sum_{j=1}^{N}\rho_{j}x_{j}'^{2})(\sum_{i=1}^{N}\rho_{i}x_{i}x_{i}')^{2}(\sum_{i=1}^{N}\sigma_{\rho_{i}}^{2})}{\epsilon^{2}(\sum_{i=1}^{N}\rho_{i})^{6}} \\ &+ \frac{\epsilon^{2}(\sum_{i=1}^{N}\sigma_{\rho_{i}}^{2})}{(\sum_{i=1}^{N}\rho_{i})^{6}} \end{split}$$

Transverse Phase Space

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- Statistical errors reflect the shot-to-shot stability



Correlation Between the Laser and the electron Beam



PHIN Photoinjector as the CLIC-DB e- Source / ICPP / 24 June 2011

A practical model for the optimization studies, C. Travier's Model



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 Production of the specified charge value, transmission,

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- Production of the specified charge value, transmission,
 - The nominal laser spot size,
 - Maximum achievable gradient,
 - The emission phase of the particles with respect to the RF field,
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Compromise between minimum emittance and minimum energy spread,

- The proper beam focusing for the emittance compensation,
- Eventually, determination of a working point for a particular set of specifications.

Beam Loading Compensation Beam Instrumentation & Characterization

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The beam loading compensation is studied and optimized for the PHIN photoinjector by adjusting the timing of the beam versus the RF pulse.

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The PHIN commissioning measurements have been performed under the conditions where the beam loading is compensated.

Background Sources for the OTR Monitoring of PHIN

Possible Sources

- > the electrons that are not stopped by the slit-mask,
- the overlapping between the individual beamlets,
- x-rays
- external light pollution
- radiation due to the heating of the OTR screen

Possible Cure

First of all, consider the intensity of the beam, gain and spectral sensitivity of the camera, type of the observation screen, always respect the signal/noise ratio.

- thickness of the multi-slit mask,
- > optimization of distance between the screen and the mask,
- shielding the camera properly,
- shielding or using a light-tight enclosure,
- offline treatment (usually the background has a Gaussian distribution in this case),



PHIN Photoinjector as the CLIC-DB e- Source / ICPP / 24 June 2011





A general remark



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As a conclusion from the ICFA Future Light Sources Conference <u>http://www-conf.slac.stanford.edu/icfa2010/</u>

 $\epsilon_n[mm\,mrad] \approx 1\mu m \sqrt{Q[nC]}$



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 $\epsilon_n[mm\,mrad] \approx 1\mu m \sqrt{Q[nC]}$

Numerical studies with PARMELA shows that:

- Provided that the working point is optimized for the proper emittance compensation, the above approximation holds,
- The proportionality constant is a function of the laser shape.
- Currently, laser shaping study in progress at PITZ.